



# First results with Hydrogenated Amorphous Silicon devices to detect ionizing radiation fluxes.

L.Servoli

and the HASPIDE collaboration



8 institutions



45 researchers



# Why a-Si:H as material?



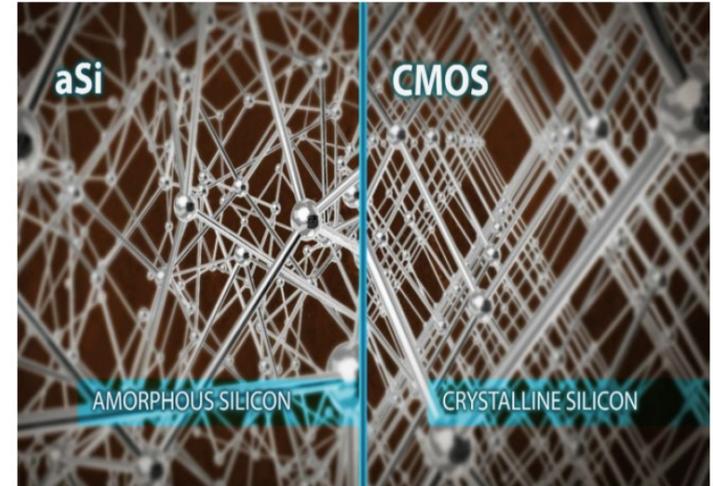
- 1969: a-Si:H synthesized for the first time by Chittik et al. from growth by plasma-enhanced vapor deposition (PE-CVD) of SiH<sub>4</sub> (Silane)
- 1976: Spear and Lecomber demonstrated that **this material could be substitutionally doped both in n and p-types**. → development of **transistors, solar cells, and memories**.
- from mid '80 on: **direct detection of ionizing radiation** based on p-i-n or Schottky diode structures (thickness 1 to 50 μm),
  - **is not good enough for Minimum Ionizing Particles** (S/N ~ 3-5 at maximum)
  - **good for ions or radiation fluxes (proton @ CNAO)**
- For **synthesized x-rays imaging (energies ~ 100 keV)** detector based on a deposited CsI layer acting as scintillator and the light signal detected by the a-Si:H p-i-n diode with an efficiency better than 70% have been developed (Flat Panel for radiography).



# Why a-Si:H as material?



- *it is intrinsically radiation resistant;*
- *it can be deposited in thin layers (~ 1-100  $\mu\text{m}$ );*
- *it can be deposited on different substrates, even flexible ones like mylar and kapton;*
- *it has a band gap value just higher than c-Si: **1.7-1.9 eV**;*
- *it has a charge collection efficiency half the c-Si;*
- *material deposition process can be done on wide areas.*





# The HASPIDE INFN Project



*Creation of thin a-Si:H (1 - 10  $\mu\text{m}$ ) ionizing radiation detectors deposited over thin plastic supports to be used for:*

- *beam monitoring of medical LINACs and other types of accelerators*
- *detection of radiation bursts in space, for example Solar Energetic Particles events;*
- *neutron detection via  $^{10}\text{B}$  deposition over an a-Si:H layer to detect  $\alpha$  produced by neutron conversion.*



# *a-Si:H* Device Production



**Several standard production techniques:**

- **PECVD (plasma enhanced chemical vapor deposition); [EPFL]**  
In the process is used a mixture of Silane ( $\text{SiH}_4$ ) and Hydrogen, with working temperature between  $160^\circ$  and  $300^\circ\text{C}$
- **Radiofrequency PECVD (RF or VHF PECVD), at various Frequencies.**

**Two new procedures are under development in the HASPIDE project:**

- **Pulsed Laser Deposition (PLD) [Lecce]**
- **Reactive Sputtering [Lecce]**



# a-Si:H Contacts: p-i-n



*p-i-n contacts: a-Si:H film between two p or n doped layers*

Wire bond Al



Intrinsic a-Si:H detector layer  
10-20  $\mu\text{m}$



70  $\mu\text{m}$  kapton



p-doped a-Si:H junction layer



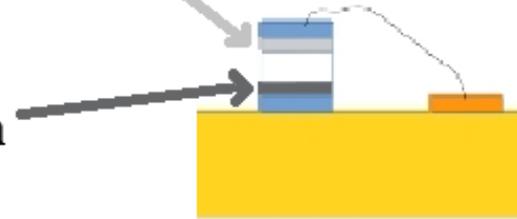
Metal layer (Cr + Al)



n-doped a-Si:H junction



detector pad or bias  
Pad in Copper

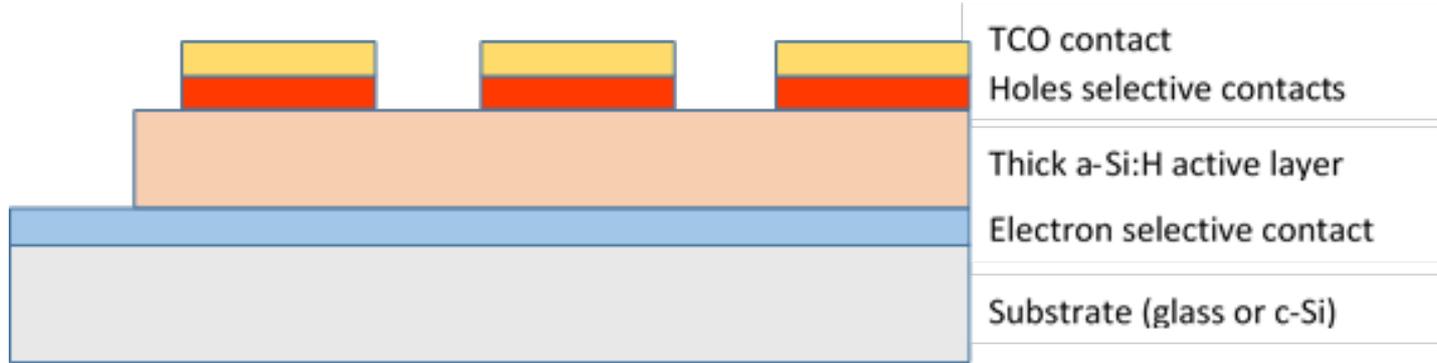


*Doped layer thickness < 30 nm; intrinsic layer (1-10  $\mu\text{m}$ )*

# a-Si:H Contacts: CSC



**Charge Selective Contacts (CSC):** two thin layers of metal oxides sandwiching the sensitive a-Si:H film.



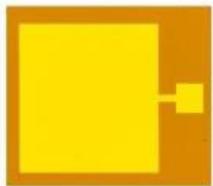
**Our first prototypes:**

- **electron selective contacts:** ZnO:Al or TiO<sub>2</sub>
- **hole selective contacts:** MoO<sub>x</sub>

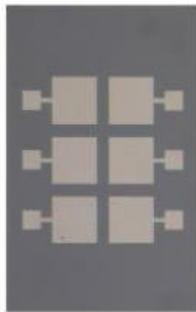
**Selective contact layer thickness < 30 nm; intrinsic layer (1-10 μm)**



# a-Si:H Devices



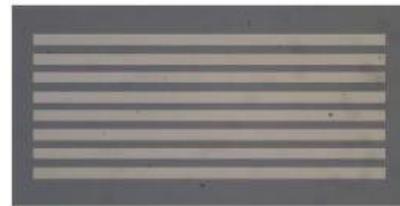
a)



b)



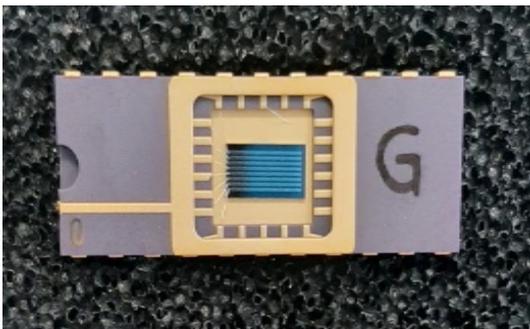
c)



d)

*Packaging: socket*

*Packaging: over kapton long tails*





# *a-Si:H* Transmission Devices



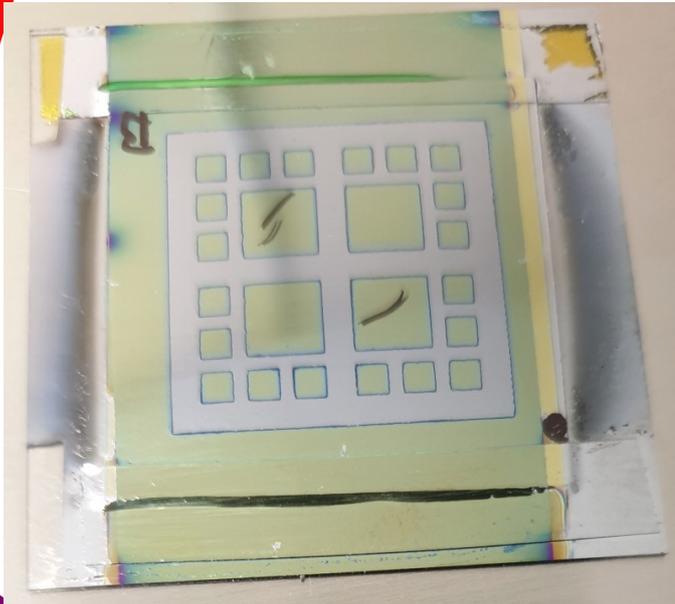
The first batch of *a-Si:H* depositions on polyamide has been produced (PECVD).

2x2 mm<sup>2</sup> and 5x5 mm<sup>2</sup> devices (p-i-n) are available for cutting and testing.

Thickness: 2.5 μm.

Polyamide thickness: 25 μm

**Goal:** produce transmission devices to monitor in real time ionizing beams, both in shape and flux

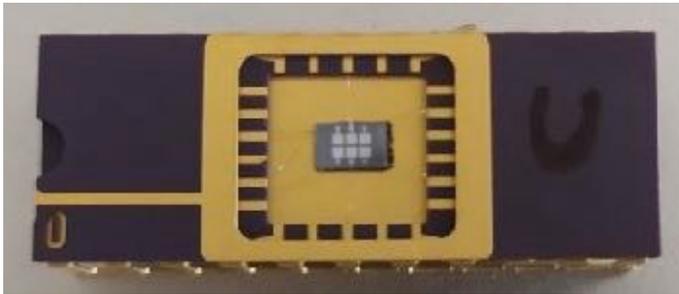




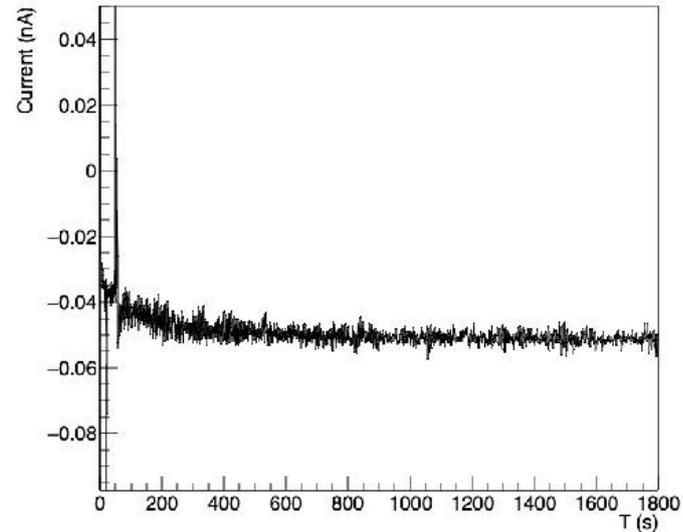
# Device characterization: noise



Noise depends on many cause. Nevertheless, given the higher band gap wrt *c-Si*, we have obtained typical noise values of the order of 10-20 pA for both *p-i-n* and *CSC* devices.



*p-i-n* pads:  
 $0.5 \times 0.5 \times 0.010 \mu\text{m}^3$   
bias 20 V

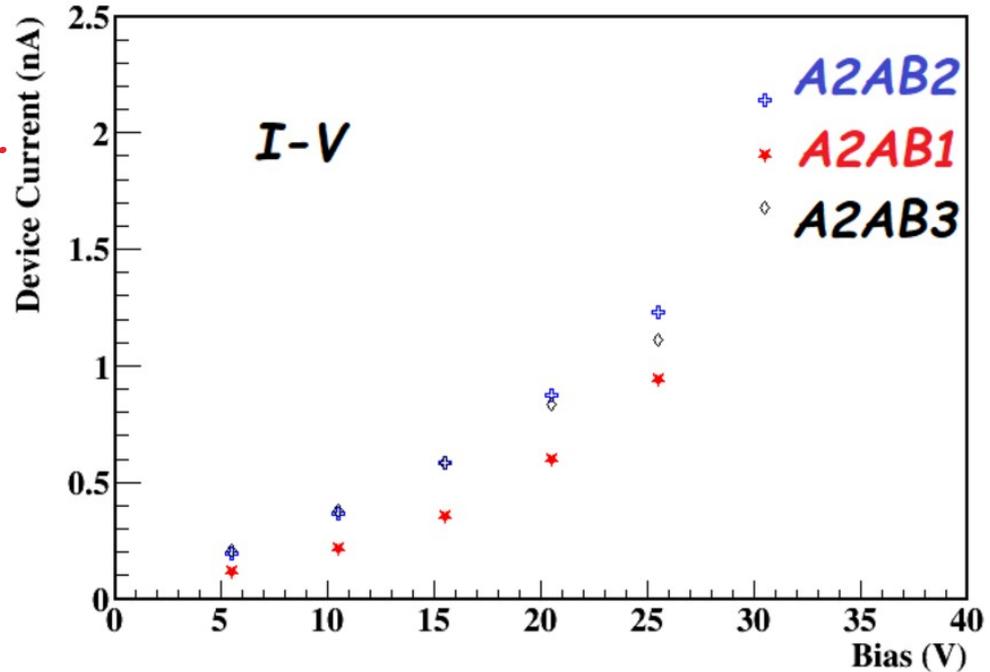
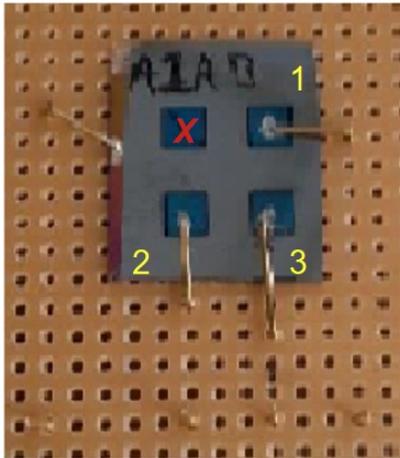




# Device characterization: I-V



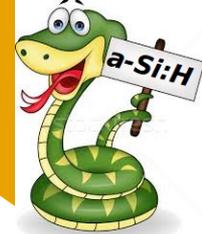
*a-Si:H structure: 4x4 mm<sup>2</sup>,  
6.2 μm thick, CSC, 20 V bias.*



*Bias up to 4 V/μm ; reasonable leakage current: 100-200 pA @ 1V/μm.  
Variation among devices: < 20 % for whole bias range.*

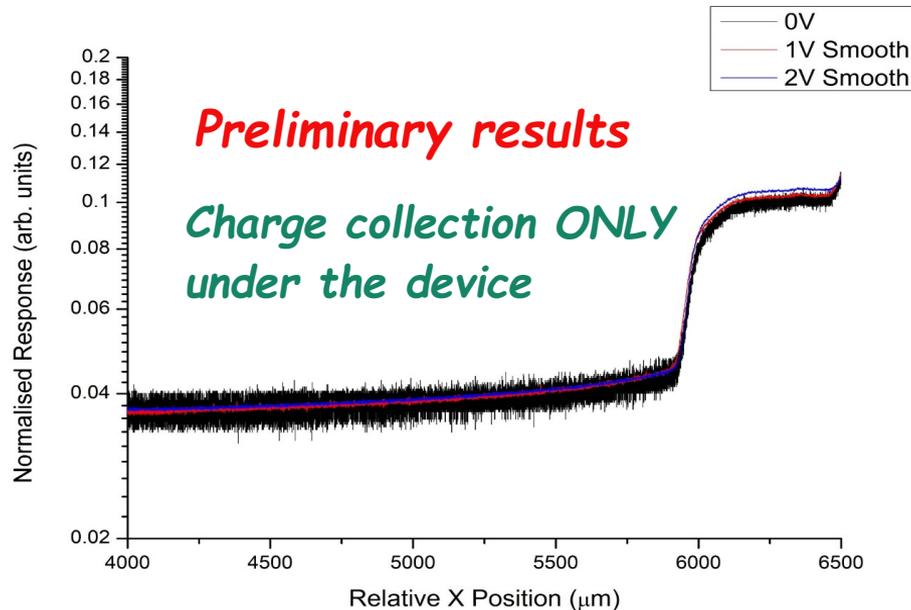
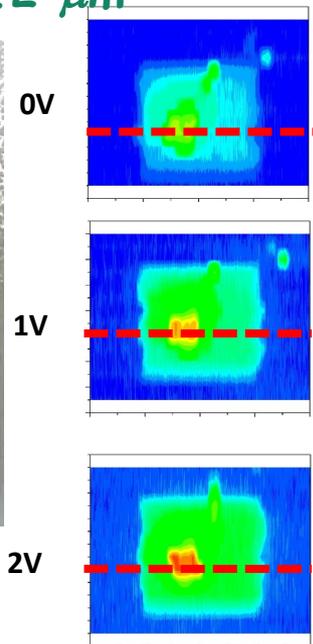
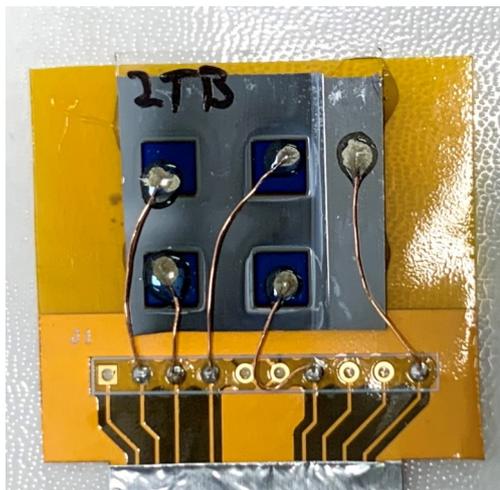


# Device sensitive volume



Some tests using microfocalized Synchrotron radiation by UOW have been done. **Preliminary results** show the signal collection as a function of the surface point where the microbeam is pointing:

CSC 4x4 mm<sup>2</sup> x 6.2 μm



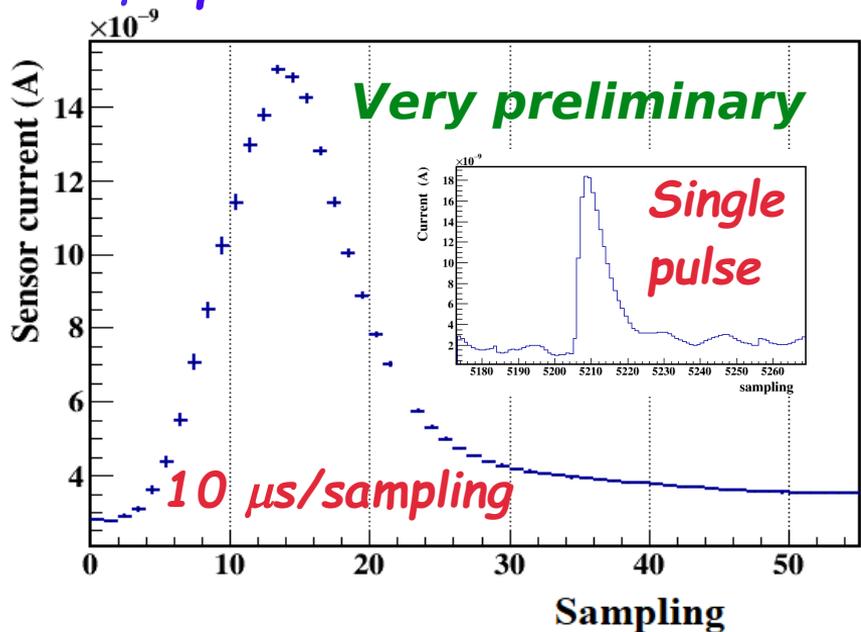
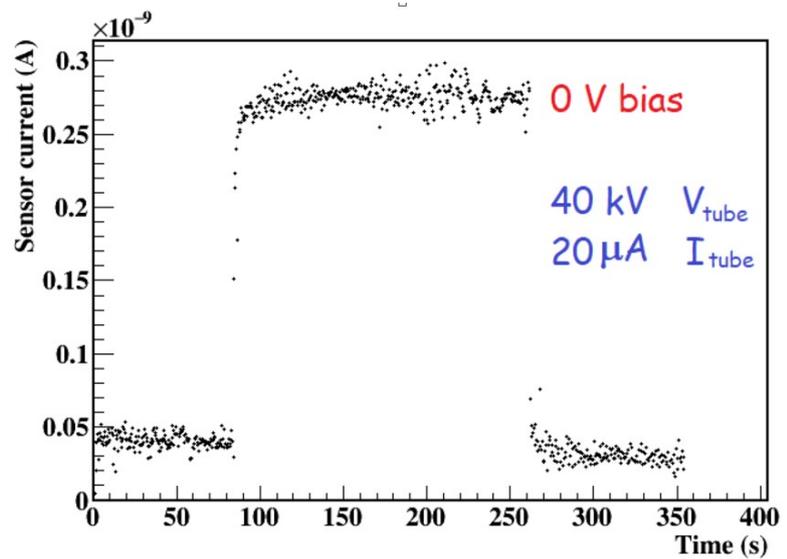


# First results: Response in time



X-ray tube: 40 kV, 20  $\mu$ A

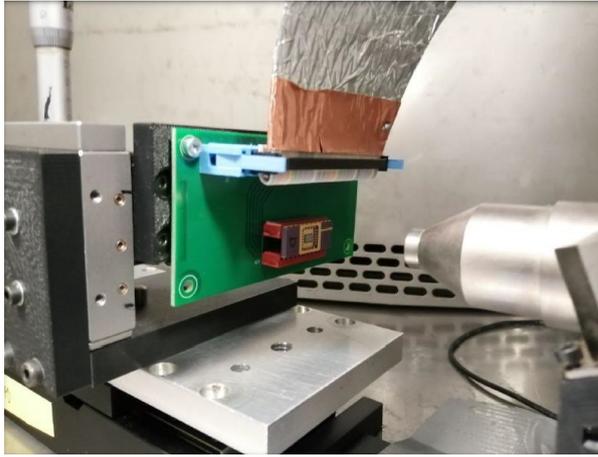
CLINAC pulse width: 6 MV,  
3  $\mu$ s pulse width.



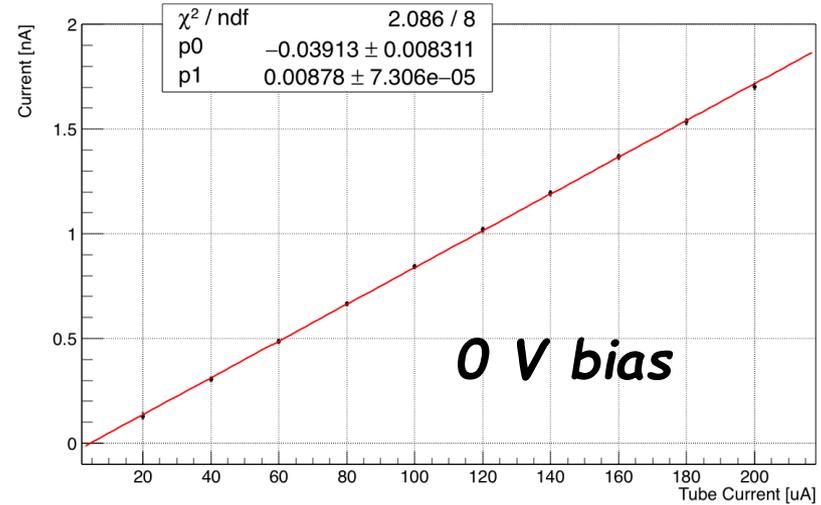
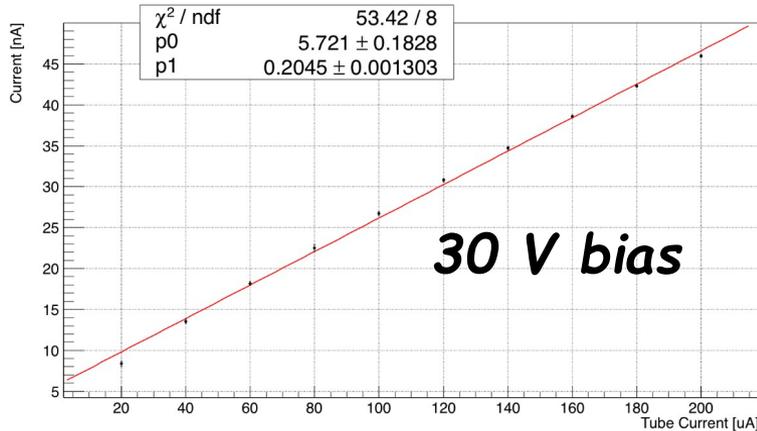
*a-Si:H* structure: 4x4 mm<sup>2</sup>,  
6.2  $\mu$ m thick, CSC, 20 V bias.



# First results: X-ray beams



**CSC 4x4 mm<sup>2</sup> device, 8.2 μm thick**  
**0 V bias, tube: 30 kV, current scan**



**Sensitivity(0 V)/Sensitivity(30 V) ~ 23**

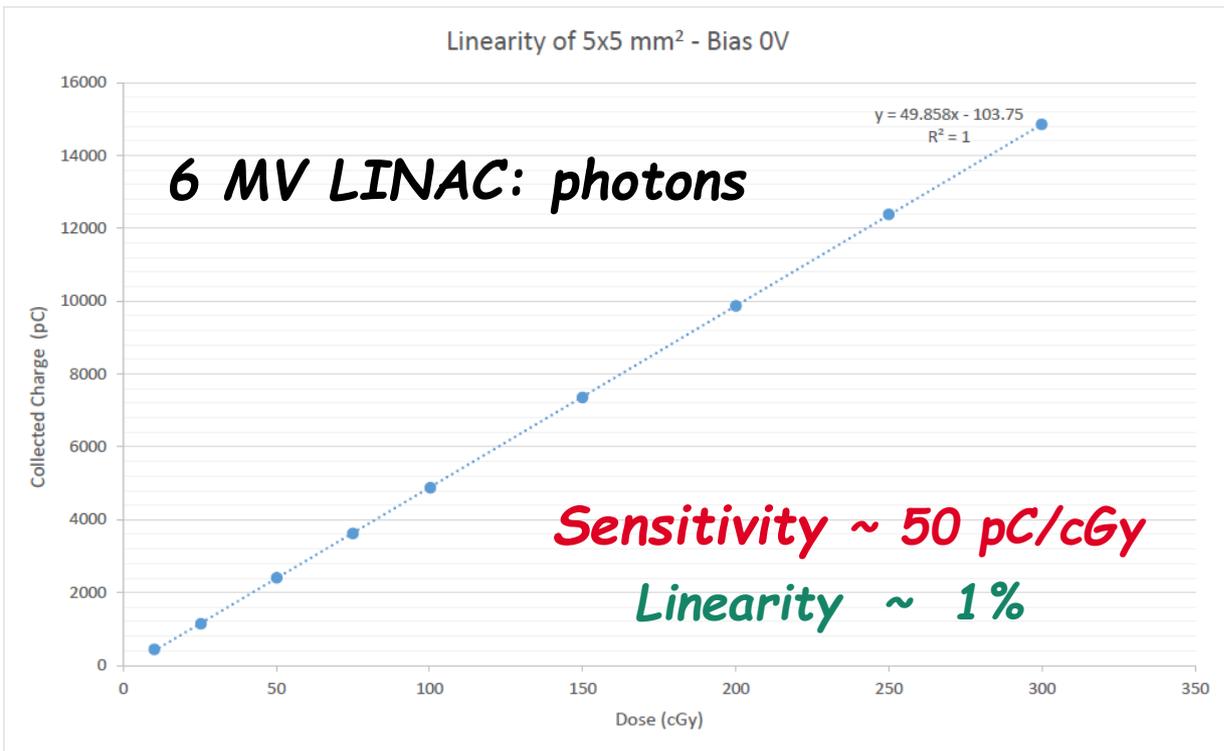
**Linearity ~ 1-2%**



# First results: Clinical LINACS



CSC 5x5 mm<sup>2</sup> device, 10 μm thick, 0 V bias



Similar results for 6 MeV electrons from LINAC

(see talk by C. Talamonti  
Sez. 5, 13/9/2022)



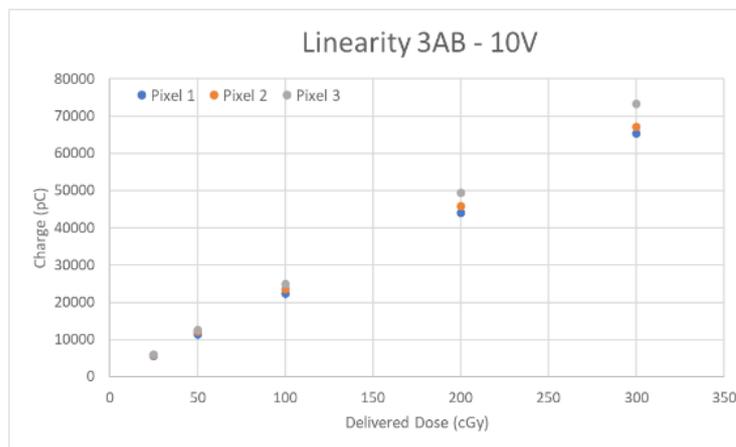
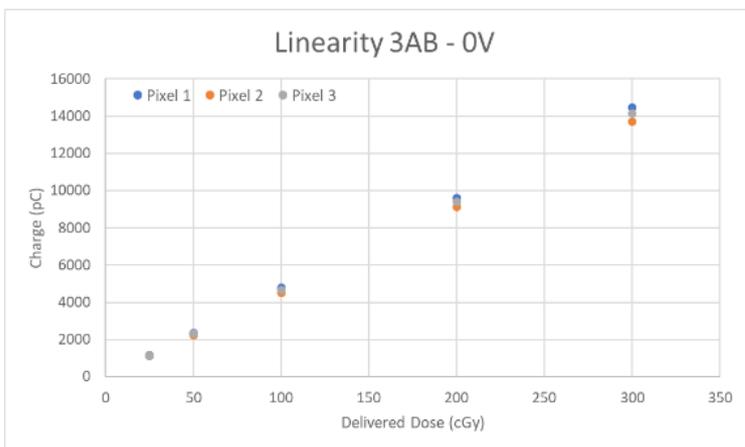
# First results: Clinical LINACS



Made by UOW at 6 MV Clinical LINAC (Photons) (CSC)

## Linearity - 3AB

- 8.2  $\mu\text{m}$  a-Si:H layer
- Al:ZnO electron selective contact



Response linearity

1-2 %

	0V (pC/cGy)	10V (pC/cGy)
Pixel 1	48.35 ± 0.03	217 ± 1
Pixel 2	45.86 ± 0.04	222 ± 3
Pixel 3	47.37 ± 0.08	245 ± 2

Device uniformity:

3 % @ 0 V; 7 % @ 10 V



# Sensitivity vs ionization source



We have tested different p-i-n devices with different type of ionizing radiation beams:

<i><b>Ionizing radiation type</b></i>	<i><b>50 kV X-ray Photons</b></i>	<i><b>6 MV Photons (Clinical)</b></i>	<i><b>6 MeV Electrons (Clinical)</b></i>	<i><b>Protons (3 MeV) preliminary</b></i>
<i><b>Sensitivity (nC/cGy)</b></i>	<i><b>1-20 (CSC)</b></i>	<i><b>0.1-1.0 (p-i-n)</b></i>	<i><b>~ 0.1 (p-i-n)</b></i>	<i><b>0.1-0.2 (p-i-n)</b></i>

Sensitivity lies in the same range

CSC devices have higher sensitivity  
→ investigation is going on



# Conclusions



- *a-Si:H material looks promising as sensitive substrate to detect ionizing radiation fluxes;*
- *very thin devices could be built (100  $\mu\text{m}$  total including incapsulation in polyamide foils);*
- *low noise, radiation hardness, reasonable uniformity among devices;*
- *response to X-ray, clinical photons and electrons is linear with dose and dose-rate and with uncertainty  $\sim 1\%$ ;*
- *next test will include more proton and ion beams tests.*





# Status of WP5: Space



We have presented the idea of measurement of Solar Energetic Particle (SEP) events at ASI Workshop with a-Si:H. Table is the minimum flux of protons at a given energy to obtain a signal bigger than 5 times the noise. Compatible with SEPs fluxes.

Proton energy (MeV)	400	200	100	70	50	20	10	5
100 pA Signal (p/s/cm <sup>2</sup> /sr)	$\sim 2 \times 10^4$	$\sim 1 \times 10^4$	$7 \times 10^3$	$6 \times 10^3$	$3 \times 10^3$	$2 \times 10^3$	$\sim 10^3$	$8 \times 10^2$

**Sensor:**  
**Dimension:**  
4x4x0.008 mm  
**Noise:**  
20 pA;  
**Sensitivity:**  
20 nC/cGy

We are writing a paper outlining the idea with some simulated performances of an instrument.